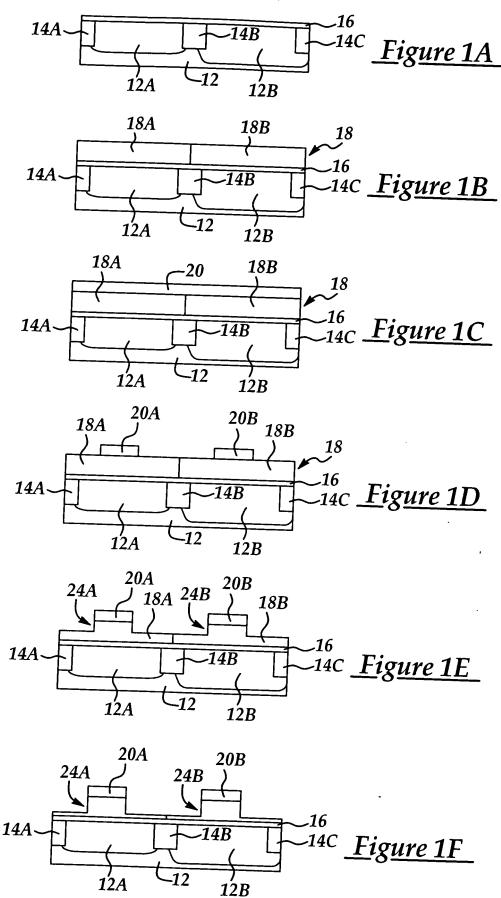
Inventor: Ming-Ching Chang

Serial No.: To Be Assigned Filed: Herewith

For: Etching and Plasma Treatment Process to Improve a Gate Profile

Attorney Doc. No.: 67,200-1107

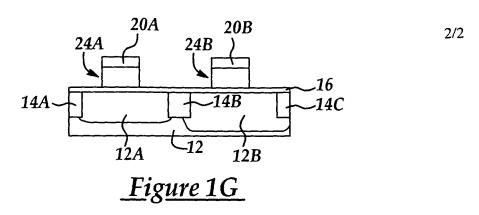
1/2



Inventor: Ming-Ching Chang Serial No.: To Be Assigned Filed: Herewith

For: Etching and Plasma Treatment Process to Improve a Gate Profile

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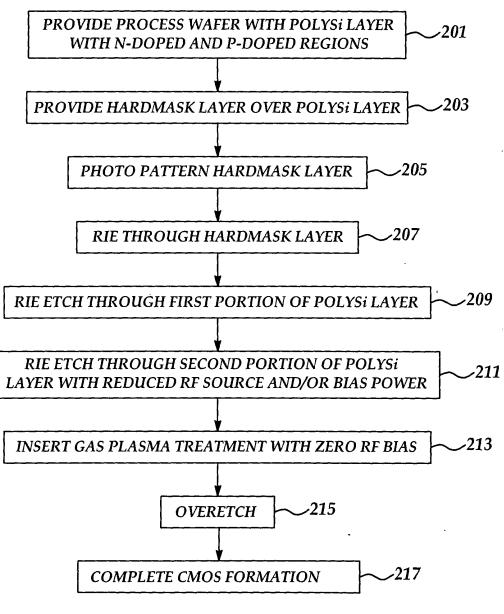


Figure 2